

Atty. Dkt. No. AMAT/6437/ETCH/METAL/JB1



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re Application of: Hwang, et al.

Serial No.: 10/092,456

Confirmation No.: 1212

Filed: March 6, 2002

For: Etching Methods for a Magnetic

Memory Cell Stack

Group Art Unit: 2818

Examiner: Dung Anh Le

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 CERTIFICATE OF MAILING 37 CFR 1.8

I hereby certify that this correspondence is being deposited on January 27, 2004, with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA

22313-1450.

Signatur

Dear Sir:

## **RESPONSE TO OFFICE ACTION DATED OCTOBER 28, 2003**

In response to the Office Action dated October 28, 2003, having a shortened statutory period for response set to expire on January 28, 2004, please enter this response and reconsider the claims pending in the application for reasons discussed below. The Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/6437/AOP, the fee of \$86, for excess claim fees, and any additional amount for other fees, including extension of time fees, required to make this response timely and acceptable to the Office.

Amendments to the claims are reflected in the listing of claims which begins on page 2 of this paper. Remarks begin on page 7 of this paper.

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